

Notice of References Cited	Application/Control No. 09/608,311	Applicant(s)/Patent Under Reexamination XIANG ET AL.	
	Examiner Paresh Patel	Art Unit 2829	Page 1 of 1

U.S. PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	A	US-			
	B	US-			
	C	US-			
	D	US-			
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FOREIGN PATENT DOCUMENTS

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NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	"Near-field Microwave Microscopy of Material Properties" by Anlage et al. University of Maryland, April 2000
	V	"An S-Band Test Cavity for a Field Emission Based RF-Gun" by T. Weis et al. Germany. pages 1471-1473.
	W	"Scanning probe microscopy for 2-D semiconductor dopant profiling and device failure analysis" by Henning et al. Thayer School of Engineering, NH, USA
	X	"Heterodyne Electrostatic Force Microscopy used as a New Non-contact test technique for Integrated Circuits" by Said et al. University of Manitoba, Canada. IEEE 1995.

*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.